

Electronic Information Disclosure Statement



IN-SITU PELLICLE MONITOR

1c474 U.S. PTO
10/064442
07/15/02

Application:
Confirmation:
Applicant(s): Michael Hibbs
Docket Number: BUR920010138
Group Art Unit:
Examiner: Unknown
search string: (5652657 or 5742386).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Citation No.	Patent Number	Date	Bar Code	Patentee	Class	Subclass
	P01	5652657	1997-07-29		Yoshii et al.	356	394
	P02	5742386	1998-04-21		Nose et al.	356	237

Remarks

(Remarks are not for responding to an office action.)

1) Abstract of JP63274131, titled EXPOSURE DEVICE, publication date: 1988-11-11, Yamamoto Yukihiro; 2) Abstract of JP4198740, titled PERMEABILITY MEASURING METHOD FOR PELLICLE, publication date: 1992-07-20, Miyashita Tomiko; 3) Abstract of JP7333827, titled INSPECTION SYSTEM FOR ORIGINAL WITH PELLICLE, publication date: 1997-07-29, Miura Seiya (JP), Yoshii Minoru (JP), Kohno Michio (JP), Takeuchi Seiji (JP), Tsuji Toshihiko (JP), Miyazaki Kyoichi (JP); 4) Abstract of JP4006559, titled METHOD FOR MEASURING TRANSMITTANCE OF PELLICLE, publication date: 1992-01-10.

Signature

Examiner Name	Date